

# Investigation of the Si doping effect on the Ga<sub>2</sub>O<sub>3</sub> films prepared by atomic layer deposition

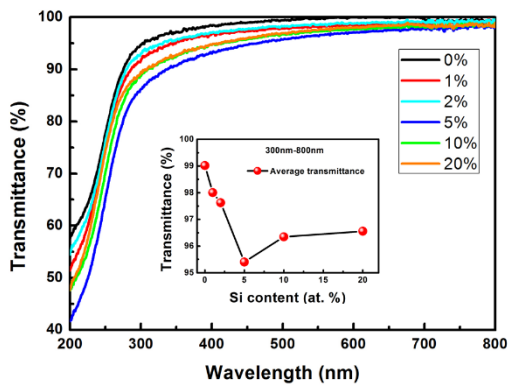
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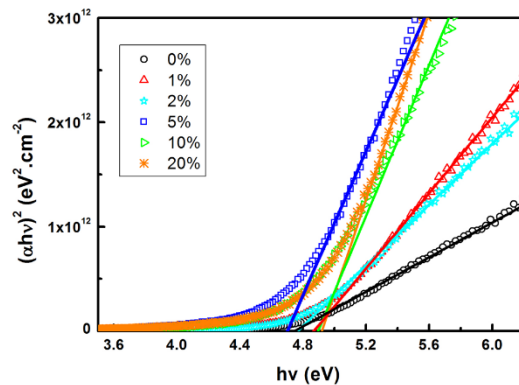
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Precise control dopant composition and systematic study the doping effect are critical to the production of functional films with desired properties. In this study, we make the original try to use atomic layer deposition (ALD) to fabricate Si-doped Ga<sub>2</sub>O<sub>3</sub> films. Optical spectrometry, Hall measurements, X-ray photoelectron spectroscopy and several other measuring techniques were applied to characterize and analyze the optical, electrical and structural properties of the doped films. The experiment results indicated that the content of the Si has an obvious influence on the photoelectrical properties of Ga<sub>2</sub>O<sub>3</sub> films. The refractive index of Ga<sub>2</sub>O<sub>3</sub> films was decreased with the increasing of the Si content. The Ga<sub>2</sub>O<sub>3</sub> energy gap can be tuned from 4.75 to 4.92 eV through Si doping. The average transmittance was larger than 95% from ultraviolet to visual wavelength for all these Si-doped Ga<sub>2</sub>O<sub>3</sub> films although the optical transparency was reduced after the Si doping. These results suggesting that the Ga<sub>2</sub>O<sub>3</sub> film-based devices such as transparent electrodes, photodetectors or thin film transistors can be further optimized the structural quality and conductivity by improving ALD process.



**Fig. 1.** Transmittance spectra for Ga<sub>2</sub>O<sub>3</sub> films varied with Si content. The insert shows the average transmittance in the wavelength of 300-800 nm as a function of Si content.



**Fig. 2.** The  $(\alpha h\nu)^2$ - $h\nu$  relation for Ga<sub>2</sub>O<sub>3</sub> films with increasing Si content.